

Fig. 1A

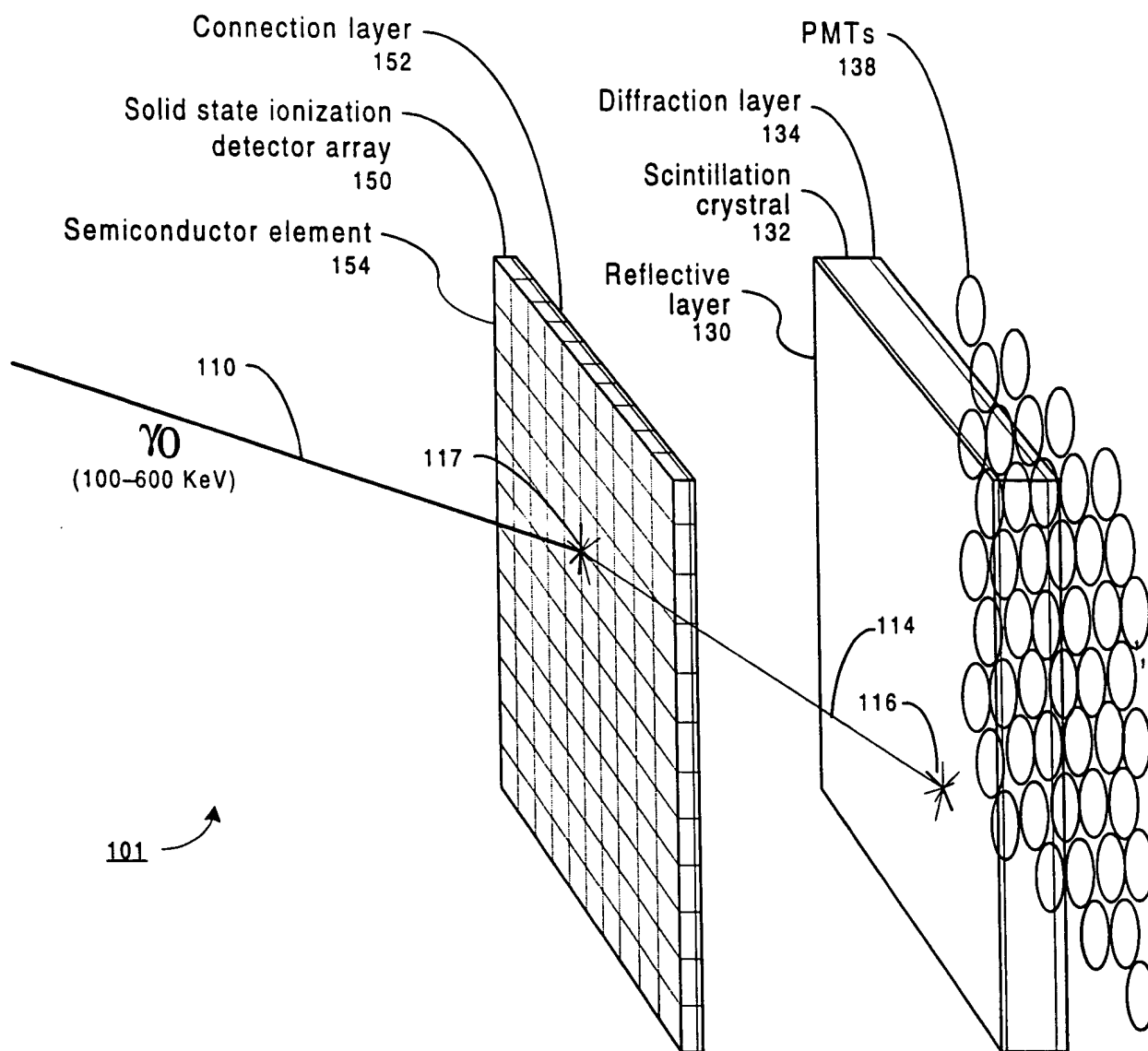


Fig. 1B

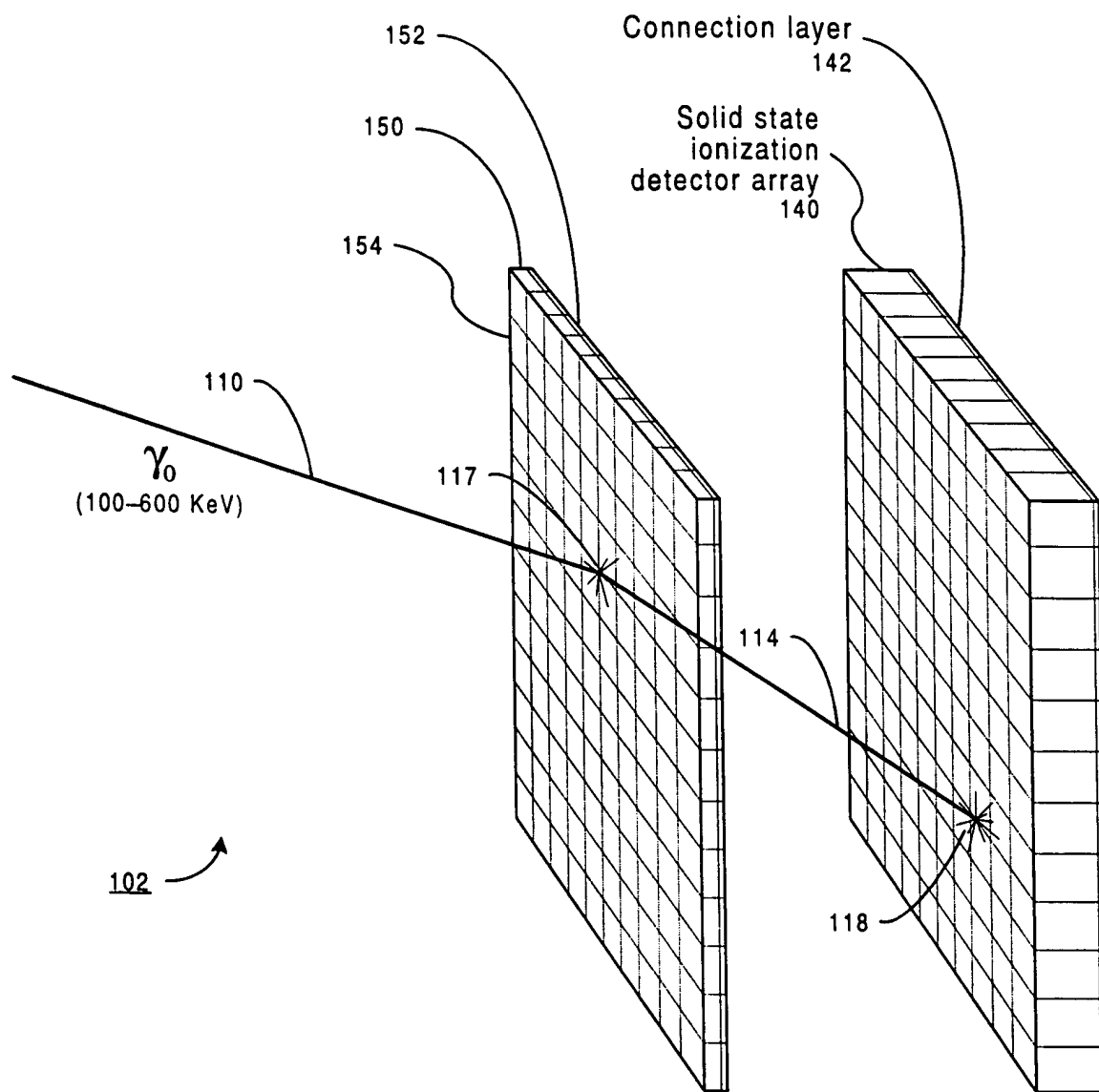


Fig. 1C

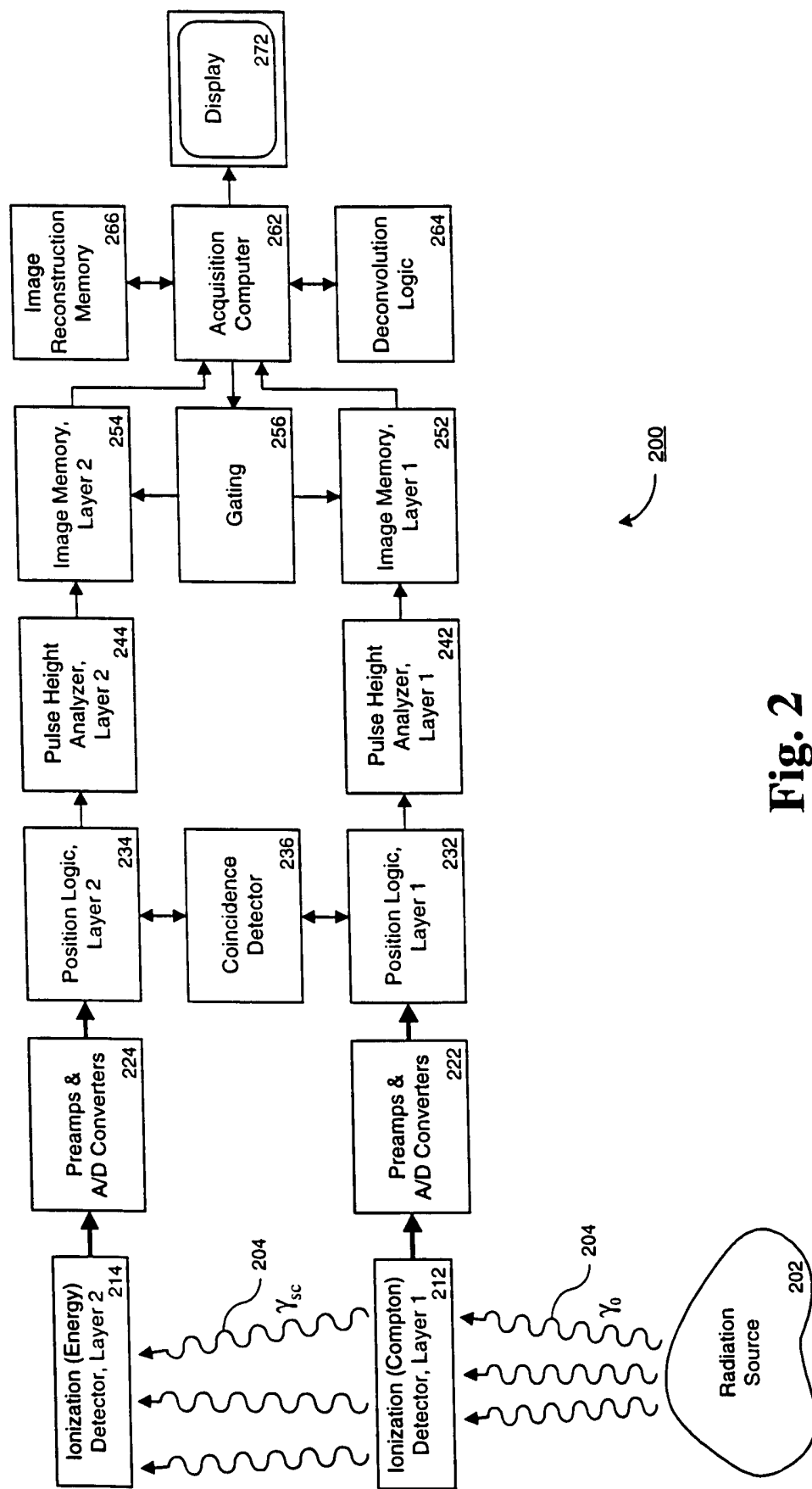


Fig. 2

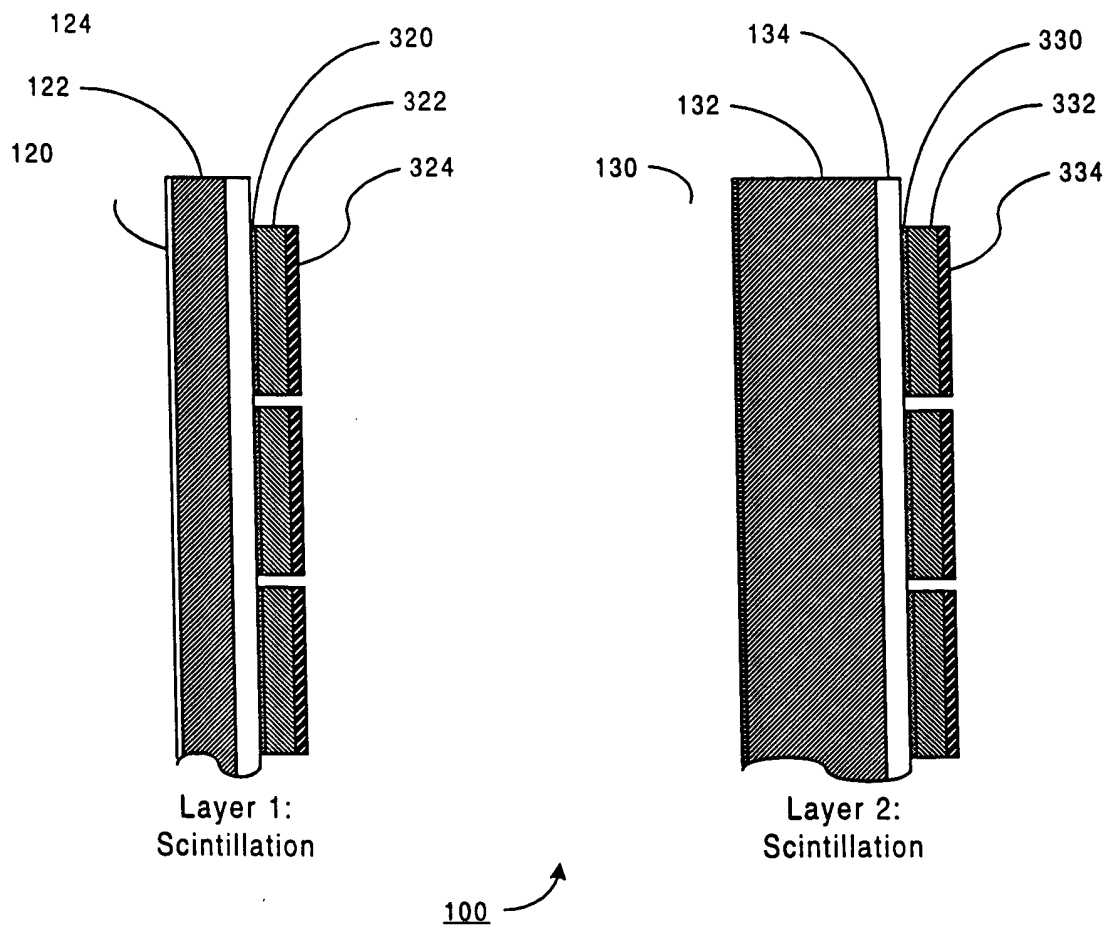
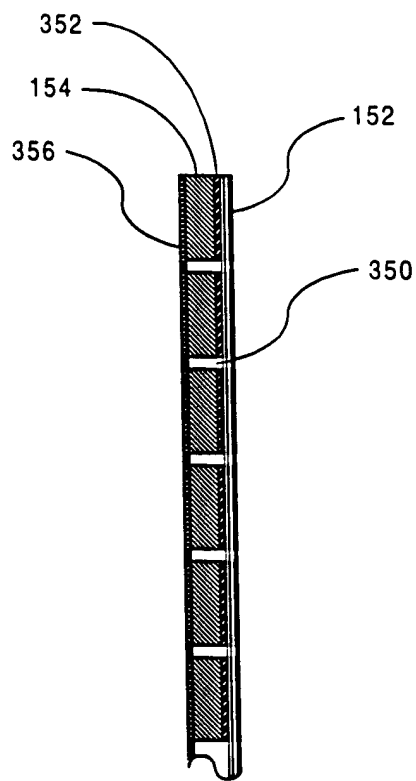
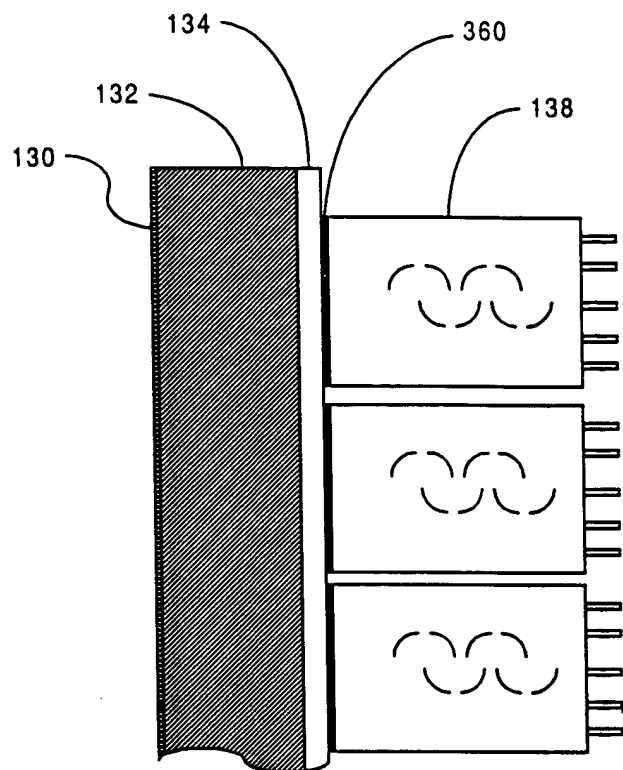


Fig. 3A



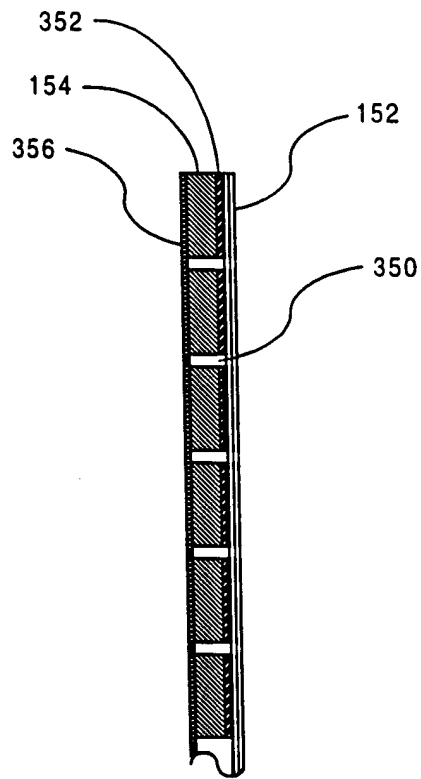
Layer 1:
Semiconductor



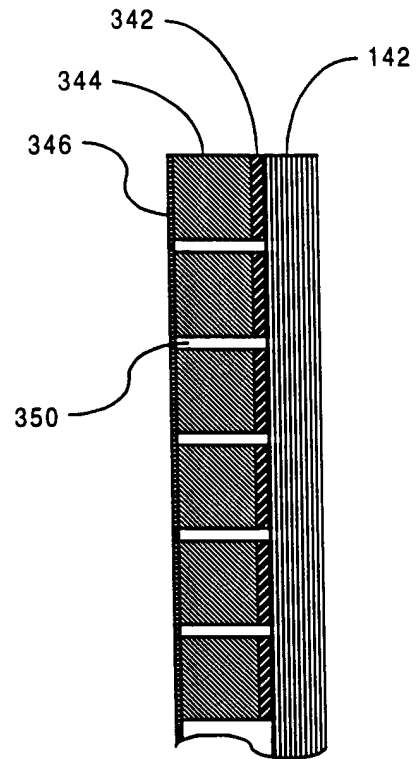
Layer 2:
Scintillation

101

Fig. 3B



Layer 1:
Semiconductor



Layer 2:
Semiconductor

102

Fig. 3C

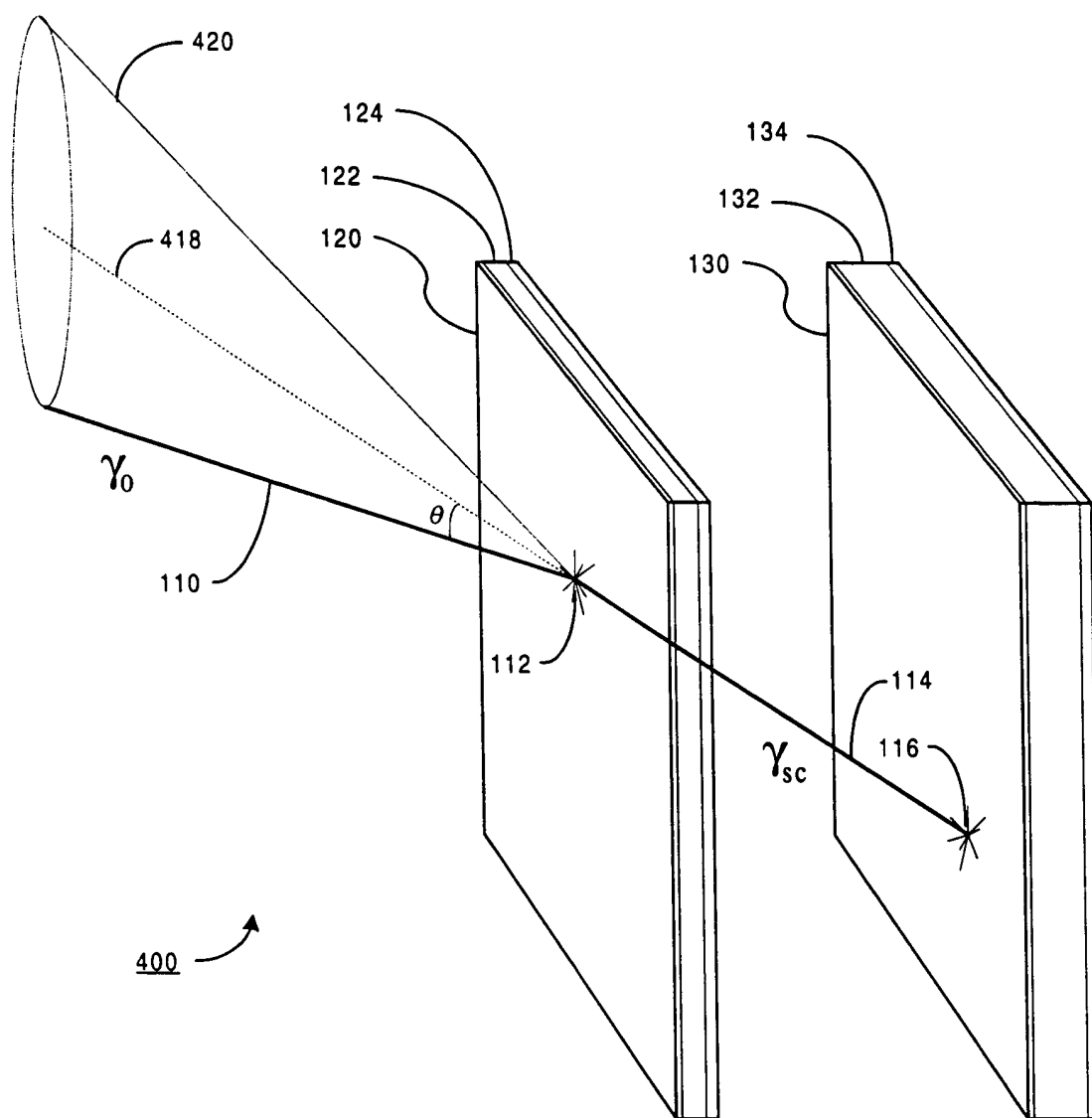


Fig. 4A

Fig. 4B

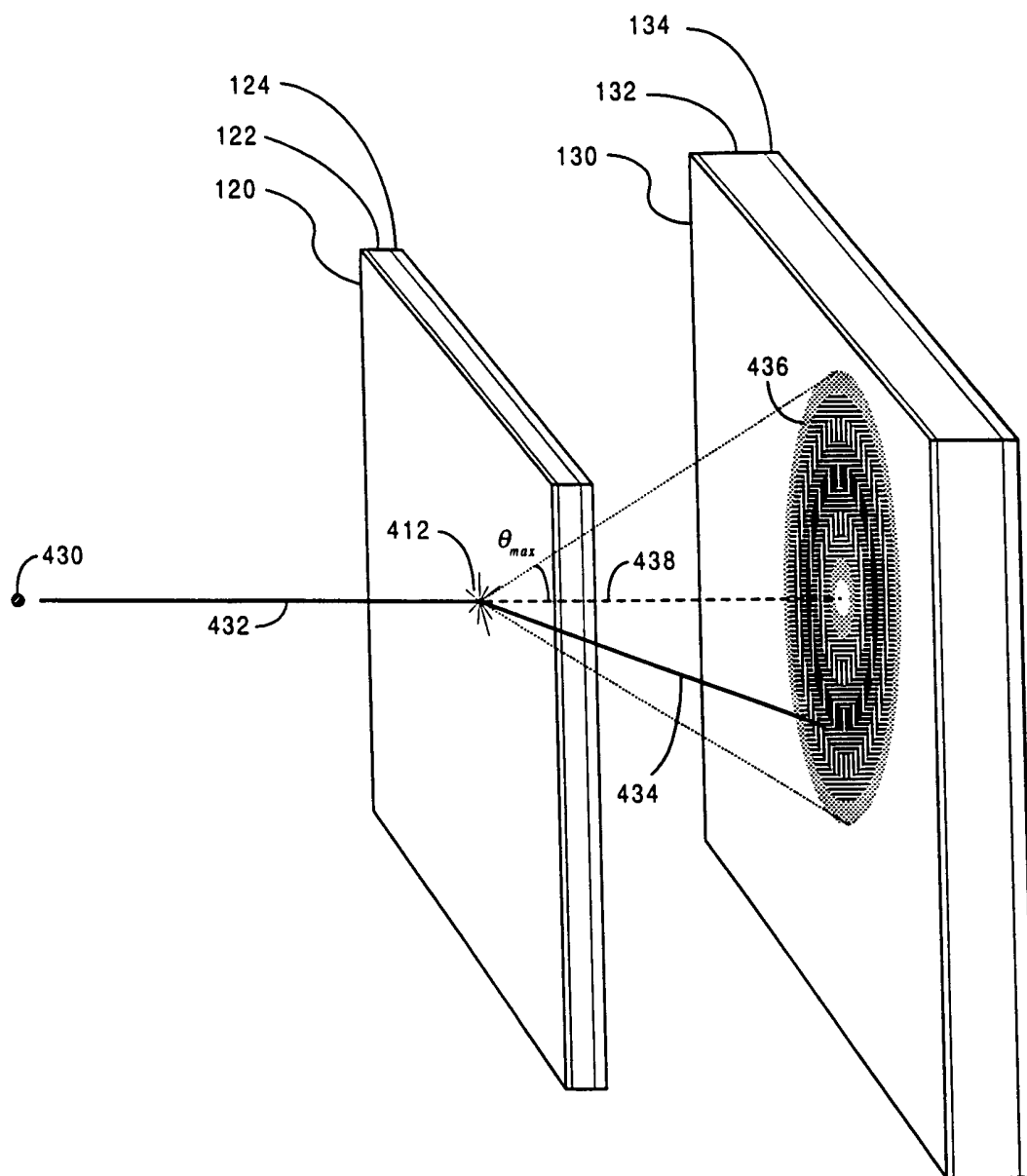


Fig. 4C

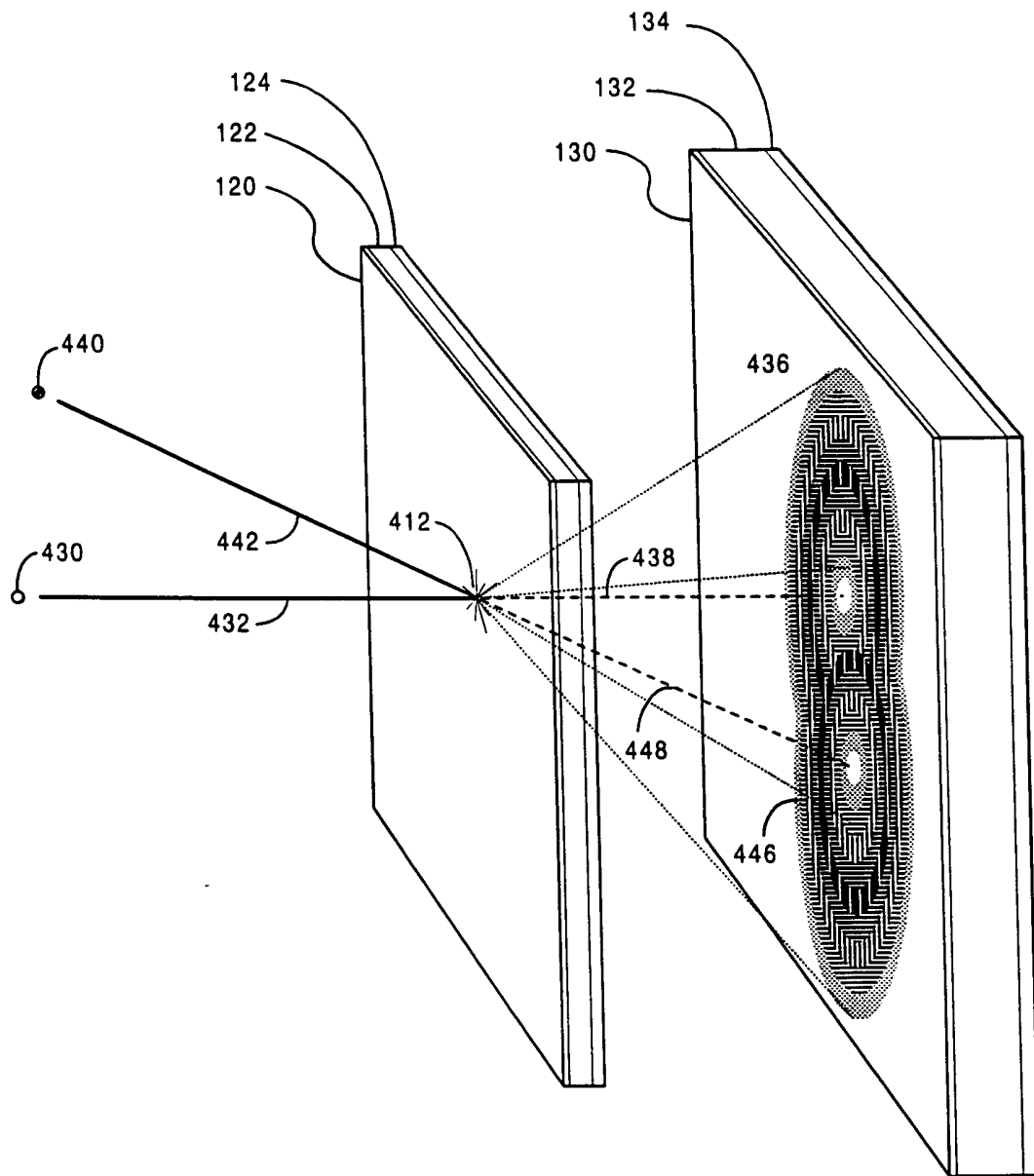


Fig. 4D

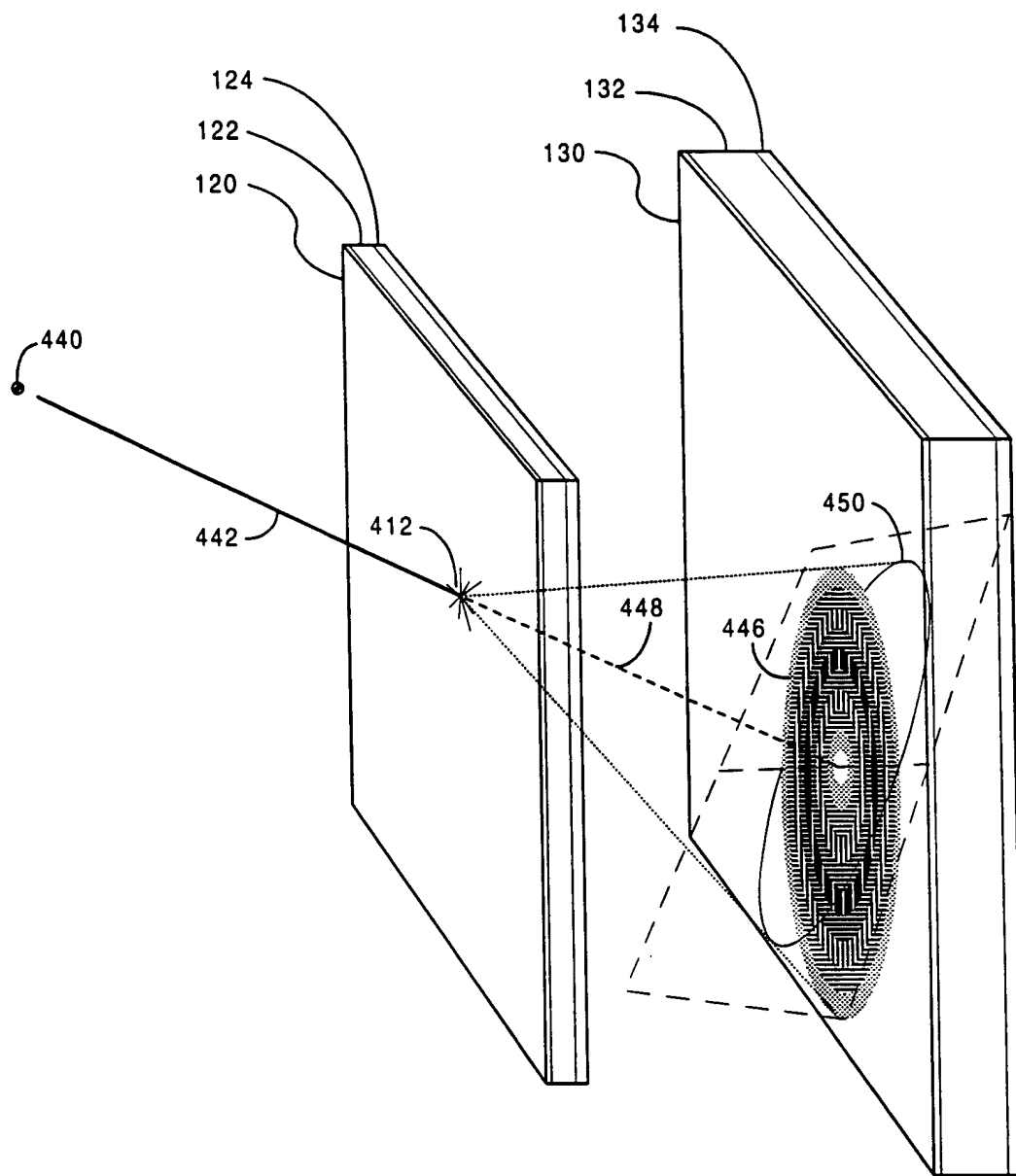


Fig. 4E

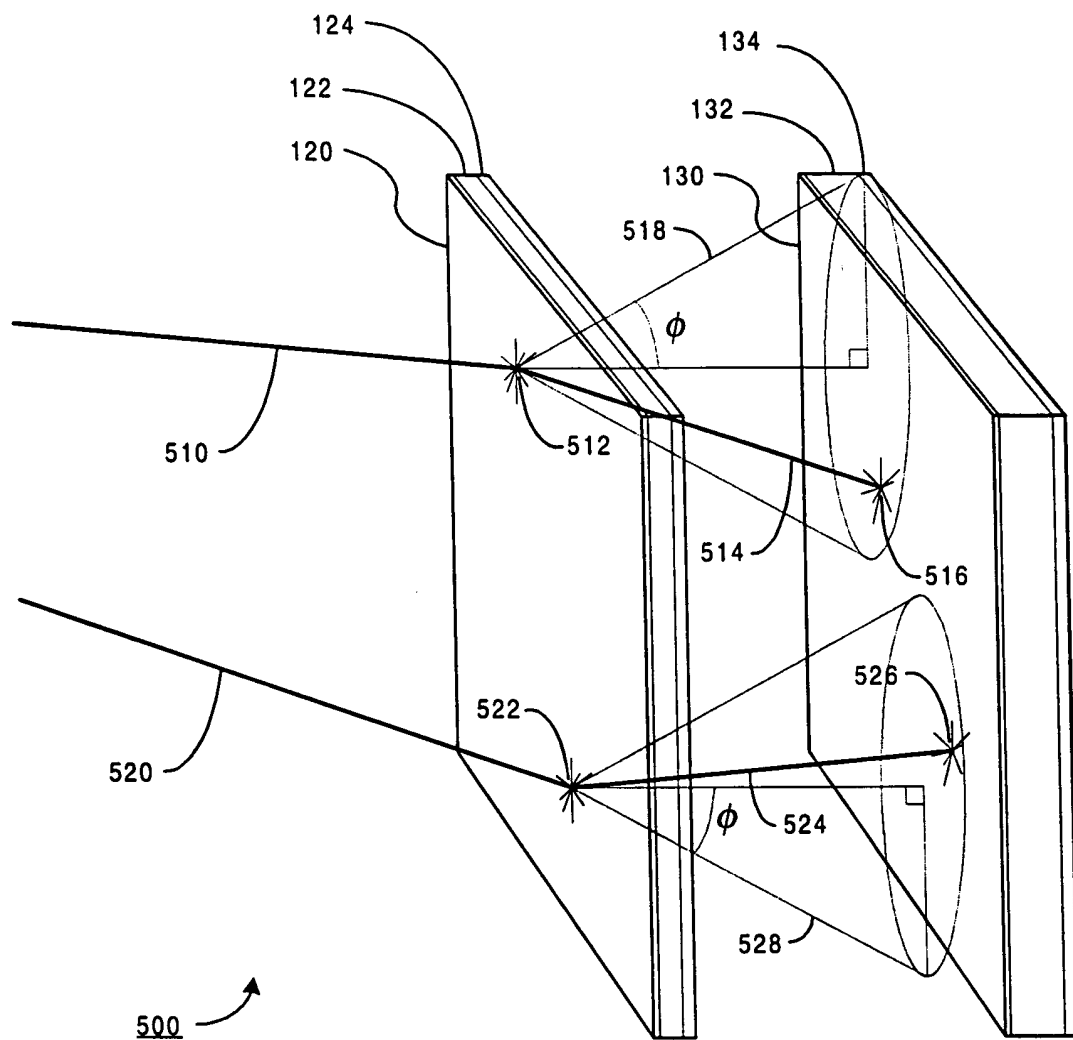


Fig. 5

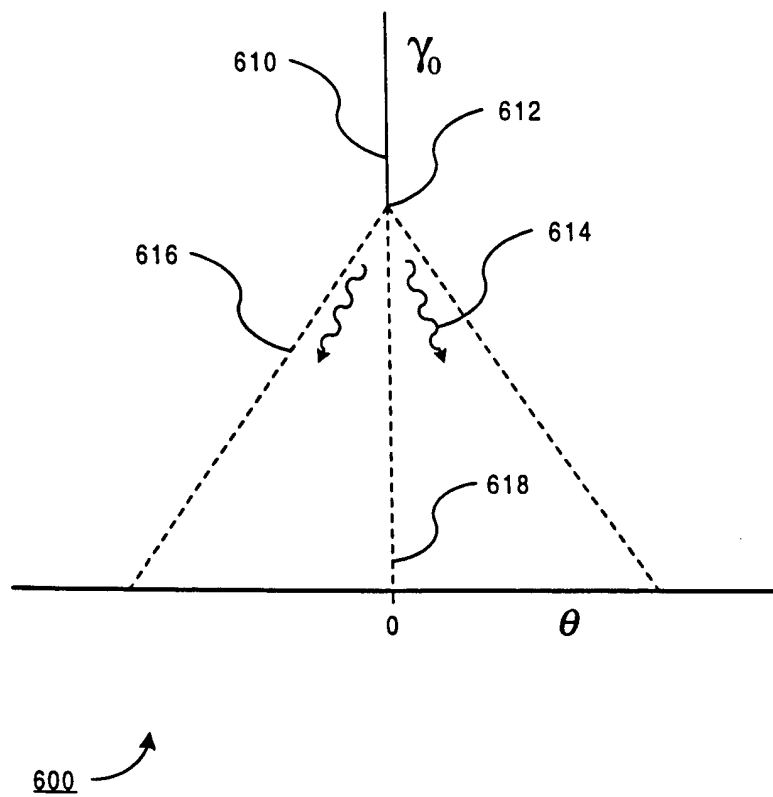


Fig. 6A

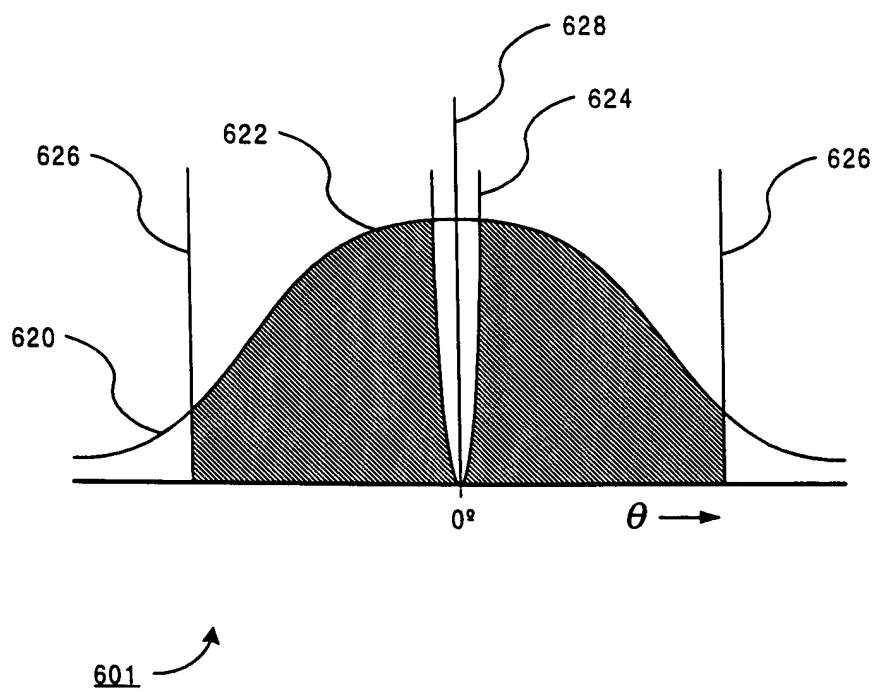


Fig. 6B

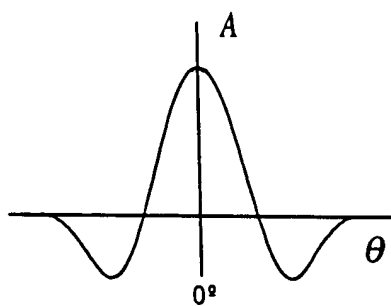


Fig. 6C

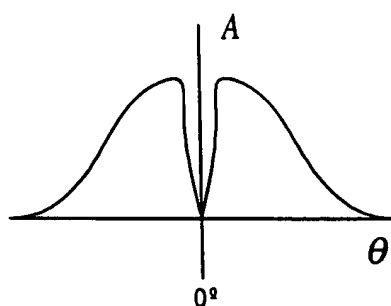


Fig. 6D

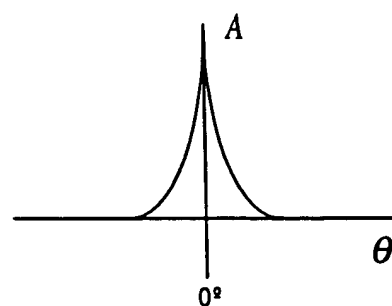


Fig. 6E

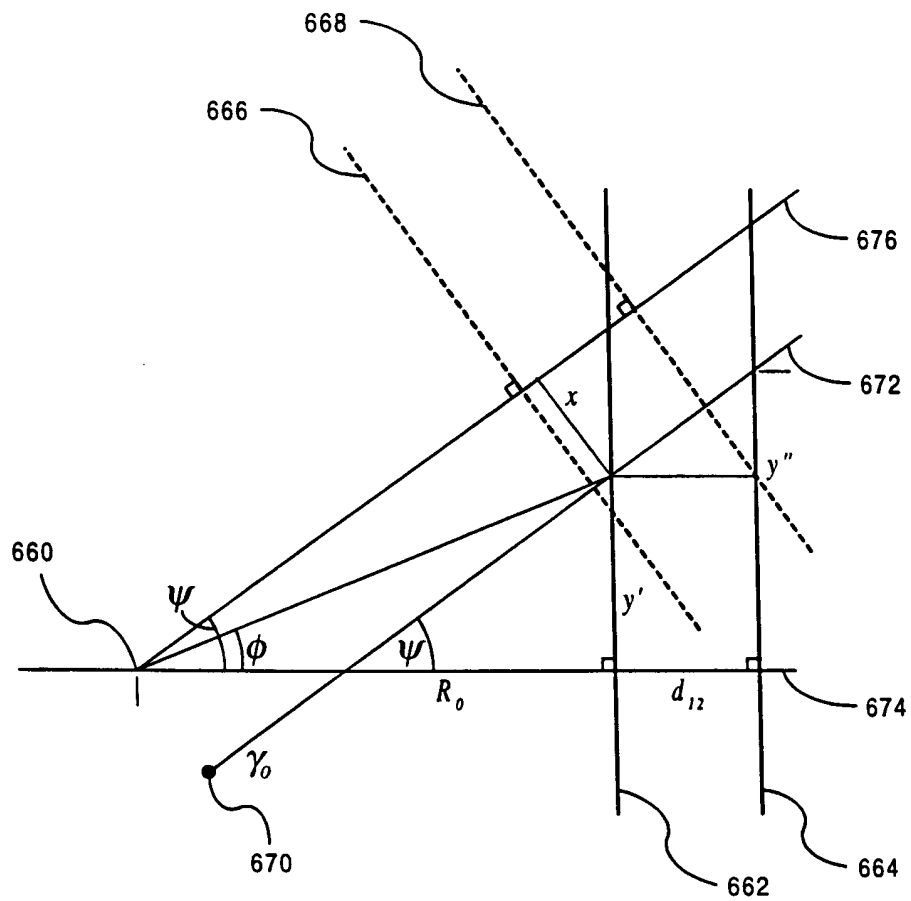


Fig. 6F

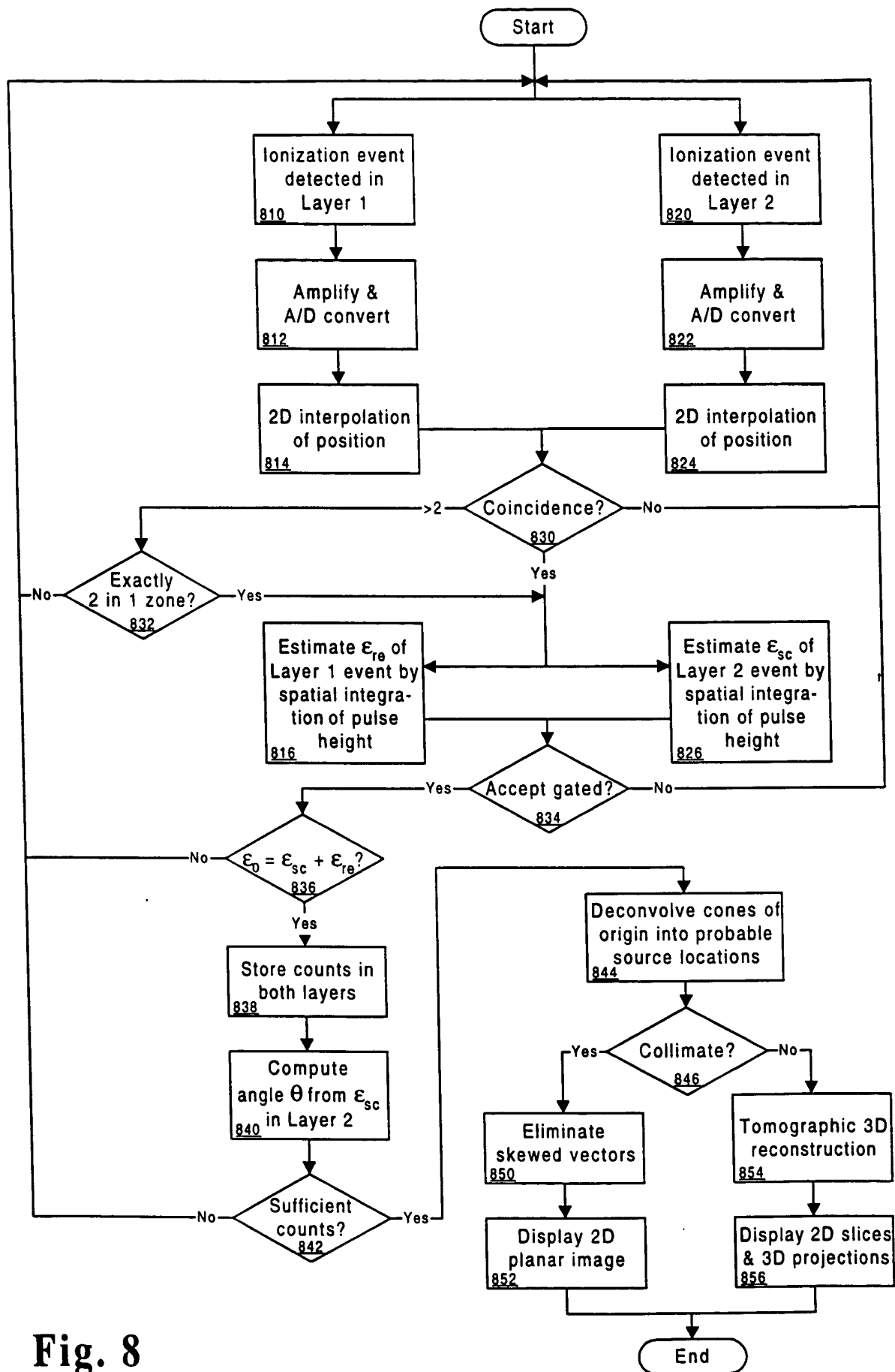


Fig. 8

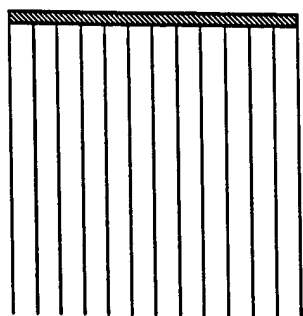


Fig. 9A

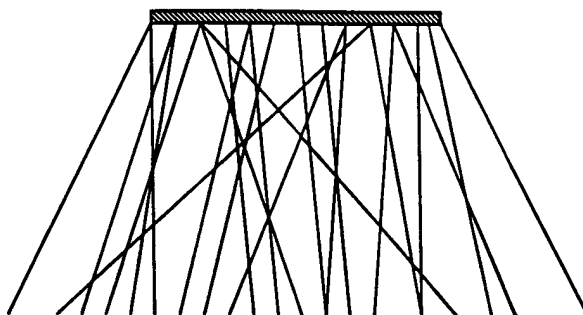


Fig. 9B

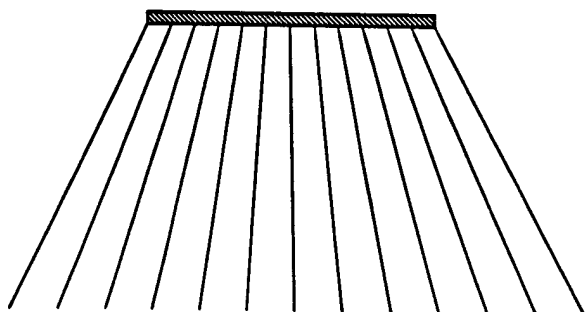


Fig. 9C

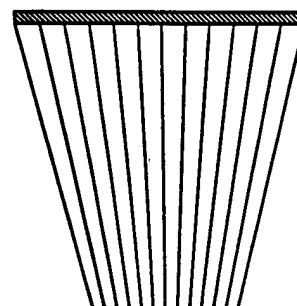


Fig. 9D

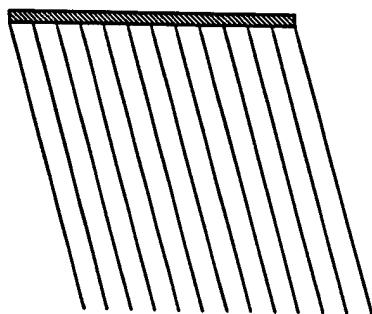


Fig. 9E

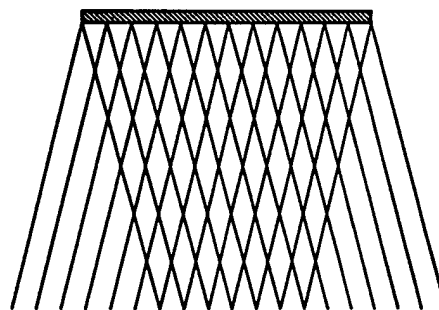


Fig. 9F